

Micro- Nanofabrication in the CNI Clean Room!

Renovated and expanded
5000 sq. ft., class 1,000/10,000

FEOL to BEOL processing - full device design and fabrication from lithography to dicing and bonding:

- Laser mask design and writing
- E-beam and photolithography
- LPCVD and PECVD
- E-beam and thermal evaporation, sputtering thin film deposition
- Wet etch and chemical clean
- Plasma RIE and DRIE with Cl and F chemistries
- Wire bonding, dicing saw, and CMP
- SEM, optical and surface profilometers

For more information please contact:

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Our facility features:

- ⇒ *Excellent uptime of cutting edge equipment*
- ⇒ *Baseline processes and equipment stability*

External users are welcome!